



**INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT**

Attorney Docket Number	4641-65666
Application Number	10/603,732
Filing Date	June 24, 2003
First Named Inventor	Oshino
Art Unit	1733 2873
Examiner Name	Not yet assigned MACK

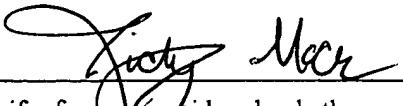
**U.S. PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
RH		5,986,827	16-Nov-1999	Hale
RH		5,249,082	28-Sep-1993	Newman
RH		4,726,671	23-Feb-1988	Ahmad et al.
RH		4,681,408	21-Jul-1987	Ahmad et al.

**FOREIGN PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Publication Number	Publication Date	Country
RH		08-68899	12-Mar-1996	Japan
RH		EP 1 312 965 A1	21-May-2003	Europe

Examiner's Initials*	Cite No. (optional)	OTHER DOCUMENTS
RH		"Construction of the Projection Optics Box for the Engineering Test Stand", presentation to International SEMATECH, by John S. Taylor, October 2000, 24 pages.
RH		"Fabrication of ETS Set II Optics: Results and Future Development", presentation to 2 <sup>nd</sup> International Workshop on EUV Lithography, by Lou Marchetti et al., October 2000, 20 pages.
RH		"High-NA Camera for an EUVL Microstepper", presentation by Layton Hale et al., October 2000, 13 pages.

EXAMINER SIGNATURE:		DATE CONSIDERED:	9/29/04
* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.			